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# Porous Silicon as a Cl<sub>2</sub> Gas Sensor at Room Temperature with Different Current Densities

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# ABSTRACT

Porous silicon exhibits characteristics of interest for the sensor device. The porous structure was formed on a silicon wafer under various anodizing conditions in an ethanol solution containing aqueous hydrofluoric acid. The observed photoluminescence at room temperature depends on the anodization time and different current densities. The porous structure formation has been confirmed by the photoluminescence as well as by scanning electron microscopic studies. In this paper, we report the sensing characteristics of porous silicon at different current densities for chlorine gas.

Keywords: Porous silicon, Photoluminescence, Current densities, Sensing.

# INTRODUCTION

Porous silicon (P-Si) has recently been discussed as a novel material for chemical sensor and biosensor [1]. Porous silicon has been proposed as a new material for the solid-state gas sensor. The sensing mechanism of the gas sensor is based on a change in the physical properties of P-Si when it is exposed to the gas. P-Si based sensors have been proposed in the literature or several applications, such as for detection of the humidity level, amount of NO<sub>2</sub> in ambient air and organic vapors concentration. The revealing of different gases like NO<sub>x</sub>, CH<sub>4</sub>, LPG, CO, H<sub>2</sub>, etc. has become extremely essential for the reason that of the unbroken increase in environmental pollution [2,3]. A number of hard works have been made in this trend over the whole humankind during the previous five decades. It essentially includes investigate for and growth of innovative resources that will give the capable outcome for the gas-sensing uniqueness [4-6]. This study is based on the discovery of the change in the electrical conductivity of P-Si when it is exposed to chlorine gas. In the future, this effect could be used as a sensing method for different chemical the gas phase. In the present work, we probe the effect of anodization parameter on P-Si sensor response.

# **EXPERIMENTAL TECHNIQUES**

P-Si films were grown on the surface at p-type Si with a resistivity of 2-ohm-cm. An ohmic contact was established one of the surfaces of each sample. P-Si was obtained by anodic etching of silicon in an electrolyte containing 48% HF and 99.86% absolute ethyl alcohol in the proportion of 1:1 ratio using secure graphite as the cathode [7]. Anodization was carried out at a current density between 30 to 70 mA/cm<sup>2</sup> for a constant time at 45 min. After anodization sample were put in HF for 1 or 2 min and dry in air. Scanning electron microscope (JEOL, Analytical Scanning Electron Microscope, and Model JSM-6360A) was used to obtain the microstructure of P-Si. All the photoluminescence

characterizations were carried out using a PERKIN ELMER LS 55 spectrometer. X-Ray diffraction (XRD) pattern for all the samples was recorded using an X-ray diffractometer (model Bruker D8 Advance) using Cu Ka radiation. The electrical resistively is measured by using two probe methods. The resistive measurements were carried out by using Keithley multimeter (model-2000) at room temperature.

## Sensitivity for gas sensing

Electrical resistivity dimensions were recorded for P-Si when they were subjected to an environment of chlorine gas. The proportion sensitivity is defined as

$$S(\%) = \frac{R_0 - R_g}{R_0} \times 100$$
(1)

Where Rg is the resistance in presence of Chlorine gas and Ro is the resistance in the air (in absence of  $Cl_2$  gas). The variation over 60 s after exposure indicates that the sample is extremely sensitive to chlorine. Figure 1 shows the variation of sensitivity for different concentrations in parts per million(ppm) of chlorine over the first 60 s. Although the samples require long periods (of around a few minutes) for reaching the saturation levels, it is suitable to take the measurements fixed interval of time.



Figure 1: Porous silicon sensitivity for Cl, gas at different current densities (mA/cm<sup>2</sup>) and time (min.).

#### **RESULT AND DISCUSSIONS**

#### XRD study

To reading the phase transparency of the resultant samples, the X-ray diffraction patterns were recorded in the  $2\theta$  range of 20-90°. The bulk XRD patterns for all the samples of the different Current density of P-Si show the presence of only one phase i.e. cubic (Figure 2).



Figure 2: XRD Spectra of (1) Crystalline silicon (2)P-Si at current density 30 mA/cm<sup>2</sup> (3) 40 mA/cm<sup>2</sup> (4) 50 mA/cm<sup>2</sup> (5) 60 mA/cm<sup>2</sup> 6) 70 mA/cm<sup>2</sup>.

# Scanning electron microscopy study

Scanning Electron Microscopy Study, it is clear that the particle sizes are in the range of 0.5-1  $\mu$ m. A random distribution and large agglomeration of particles are observed for the samples modified with current densities. At 60 mA/cm<sup>2</sup> and 70 mA/cm<sup>2</sup>, the particle distribution is more uniform with less agglomeration nature. This may have some correlation with the higher sensing performance value for the sample having 60 mA/cm<sup>2</sup> and 70 mA/cm<sup>2</sup> since the microstructure is more uniform and less agglomerated.

# Photoluminescence study

From the Figure 3 Photoluminescence Spectra at different current densities, P-Si structures have been reported to luminescent efficiently in the near infrared (IR) in the whole visible range and in the near ultraviolet (UV). The absorption coefficient has been measured in P-Si by photoluminescence. Transmission spectra are shifted towards higher energy compared to bulk Si with a shift which increases with increasing porosity. This observation is consistent with the quantum confinement model. P-Si is a two-fold promising material for sensor applications. On one side, its electrical and optical properties strongly depend on the environment, because of its large specific area. Useful sensing parameters include, for example, the electrical conductivity and photoluminescence. Most sensing parameters can effectively work at room temperature. From photoluminescence spectral range blue-red with peak wavelength 400-800 nm which is related to slow (S) band. The S-band can be tuned from close to the bulk silicon bandgap through the whole visible range. The large spectral width comes from inhomogeneous broadening and vibronic coupling of the radiative transitions. The S-band efficiency is not proportional to the inner surface area, porosity has to be exceeded to achieve an efficient luminescence. Post-anodization chemical etching in HF, corresponding to a porosity increase, results in a strong rise in PL efficiency and a blue shift of the visible band [8-10].



Figure 3: Photoluminescence spectra at different current densities (1) P-Si at current density 30 mA/cm<sup>2</sup> (2) 40 mA/cm<sup>2</sup> (3) 50 mA/cm<sup>2</sup> (4) 60 mA/cm<sup>2</sup> (5) 70 mA/cm<sup>2</sup>.

### Sensor study

Table 1 shows the average particle size data for all samples estimated by XRD and SEM measurements. The sample with 60 mA/cm<sup>2</sup> and 70 mA/cm<sup>2</sup> showed the smallest particle size and the highest sensing performance for  $Cl_{2}$ gas. This may be due to the smallest particle size as it offers a higher surface area and enhances the sensitivity very effectively. The surface area plays an important role. Higher surface area leads to a higher concentration of chemisorbedair species which further increases the change in the conductance during the adsorption of reducing gases. Finally, this gives the higher sensitivity values to the semiconducting material. Variation in the resistivity, with changes in the ambient conditions, was used as the parameter for determining the sensitivity of the conducting polymer-based sensor. Planar electrical resistivity was monitored across the two parallel strip electrodes separated by 6 mm. The resistivity of the sample was seen to increase with exposure to chlorine gas. Sensitivity is determined from the modulus of change in the value of resistance as shown in Equation (1). Variation in the resistance between the two electrodes was measured as a function of time after introducing the gas, in the 20l enclosure, which was kept in a normal ambient pressure and temperature. This parameter was useful for understanding the time response for various levels of injection for chlorine gas, ranging from 100 to 500 ppm, in terms of sensitivities of the samples as shown in above Figure 1. As expected the sensitivity increases with the concentration of gas. The resistance of the sensor is seen to increase rapidly up to 60 s, which is followed by slow saturation. The percentage sensitivity was therefore determined from the value of resistance recorded at 60 s, for each ppm level of gas studied. Variation in the sensitivity as a function of different ppm levels at 60 s for chlorine gas is plotted in above Figure 1. This plot shows an almost linear response of the sensor for the concentrations of chlorine gas varying from 100 to 500 ppm at 60 s. The recovery of the sample in the ambient condition (25°C) was seen to be quite slow (in h). Looking at this constraint it is felt that such a sample can serve the purpose of efficient sensing materials if it is employed in one-time sensors or for threshold detectors. However, recovery time was reduced from 24 h to 5 s when the sample was heated to about 45-50°C. Moreover, the resistance of the sensor returned to its base value after the heating cycle. In such situation (elevated temperatures), the sensor need not be called as one-time sensor and can be repeatedly used for a number of cycles.

**Table 1:** Porous silicon sensitivity for  $Cl_2$  gas at different current densities (mA/cm<sup>2</sup>) and time (min.) also PL peak band gap andintensity values observed at different current densities.

Current Density at mA/ cm <sup>2</sup>	Time (min)	PL wavelength (nm)	PL Peak Band Gap (eV)	PL Peak Intensity (a.u.)
30	45	590	2.1	36.544
40	45	595	2.08	32.509
50	45	600	2.06	35.397
60	45	610	2.03	84.119
70	45	620	2	126.33

# CONCLUSION

We have successfully prepared porous structure on silicon wafers under various anodization conditions and different current densities. Photoluminescence at room temperature was observed to be maximum for a current density of 70 mA/cm<sup>2</sup> and anodizing time of 45 minutes. XRD studies reveal that an optimum pore size is found at this anodizing condition and the crystal structure is cubic. The P-Si sample shows good sensitivity to  $Cl_2$  gas at the different current density and also the sensitivity depends upon porosity.

#### REFERENCES

- Arakelyan, V.M., et al., 2007. Hydrogen sensitive gas sensor based on porous silicon/TiO<sub>2-x</sub> structure. *Physics E*, 38(1), pp. 219-21.
- [2] Jayachandran, M., et al., 2001. Synthesis of porous silicon nanostructures for photoluminescent devices. *Mater Phys Mech*, 4, pp. 143-47.
- [3] Bhave, T.M., et al., 1996. Improvement in the photoluminescence efficiency of porous silicon using high-energy silicon ion irradiation. *J Phys D: Appl Phys*, 29(2), pp. 462-65.
- [4] Moseley, P.T., 1987. Solid state gas sensors. Tofield, B.C.(Eds.), Adam Hilger, CRC Press, Bristol.
- [5] Morrison, S.R., 1987. Selectivity in semiconductor gas sensors. Sensors and Actuators, 12(4), pp. 425-40.
- [6] Sberveglieri, G., 1988. Radiofrequency magnetron sputtering growth and characterization of indium-tin-oxide (ITO) thin films for NO<sub>2</sub> gas sensors. *Sensors and Actuators*, 15(3), 235-42.
- [7] Khoshnevis, S., et al., 2006. Observation of oxygen gas effect on porous silicon-based sensors. *Thin solid films*, 515, pp. 2650-54.
- [8] Gaburro, Z., 2001. Structural and optical properties of silicon nanocrystals grown by plasma-enhanced chemical vapor deposition. *Journal of Nanoscience and Nanotechnology*, 1(2), pp. 159-68.
- [9] Sakhare, Y.S., et al., 2014. Materials Research Bulletin, 59, pp. 205.
- [10] Tank, C.M., et al., 2011. Electric field enhanced photocatalytic properties of TiO<sub>2</sub> nanoparticles immobilized in porous silicon template. *Solid State Sciences*, 13(8), pp. 1500-04.